

IAP activities in 2021: Be-based coatings with pre-defined properties (incl. SEM, XRD, GDOES, TDS characterization) produced for analyses and plasma experiments – plans and capabilities

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Deposition process





Schematic description of the coating system used for Be-D (Ne, N, He) layer deposition Deposition system used for obtaining Be(-C)-D layers (with He inclusions.)





Schematic description of the coating system used for Be-D JET-like pulses layer deposition



Production of Be-based coatings - SEM





500 nm deposition

1 micron deposition

5 microns deposition

SEM images for Be co-depositions on Si substrate





Diffractograms for 1 micron Be co-deposited with D or He on W substrate, at 300°

Hexagonal beryllium polycrystalline -sharp peaks for all preferential orientations especially for Be (100), Be (002) and Be (101).

NO significant variation on different gas or with temperature.





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Monoenergetic protons with an energy of 2.6 MeV

Sample	Be (at%)	He	D
		(at%)	(at%)
Be-He, R.T.	96.5	3.5	-
Be-D, R.T.	95.2	-	4.8
Be-He, 300°C	98.2	1.8	-
Be-D, 300°C	96.4	-	3.6

Be-D and He atomic ratio extracted from simulated RBS spectra







Be+D(5%), Ra = 100nm	7,455E17 D/cm ²
Be+D(5%), Ra = 500nm	8,268E17 D/cm ²
Be+D(5%), Ra= 2000 nm	1,065E18 D/cm ²







Be_D_Ra 100nm_T 100° C



Be_D_ Ra 2000nm R.T.













Production of Be containing reference samples:

- Pure Be, binary and ternary mixed layers (Be-W, Be-C, Be-C-W, etc.) without gaseous inclusions using TVA method having controlled roughness.
- Pure and binary mixed layers (Be-W, Be-C, etc.) having up to two gaseous inclusions (D, O, N, He, Ne, etc)
- In 2019-2020 we produced thick (5 μ m) reference samples. With various imposed compositions Be(-C) samples with gas inclusions (H, D, He, N, O) Different temperatures or heat/cooling scenarios available

Pre-characterization before sample delivery:

RBS, XRD, TDS, SEM measurements in order to have preliminary information on samples structure and morphology.

Be facility setups and capabilities

Up to 6 magnetrons deposition chamber for Be reference samples with gaseous inclusions using DC and short pulse HiPIMS

Metallic impurities addition possible





Help Slide 1



Analysis of dust by ICP-OES

D1 - Divertor dust (2015-16) Sample ID -**ILW 3-5** D2 - Divertor dust (2014)-6





ICP-OES results

Sample	Divertor dust (2015- 2016) Sample ID – ILW 3-5	Divertor dust (2014)-2	Divertor dust (2014)-6
Element	Relative weigh	t ratio, % /	sample
Be	38,47	53,61	91,08
Cr	2,48	1,65	0,06
Cu	29,72	0,88	0,36
Fe	15,20	6,67	2,08
Мо	5,85	32,46	4,18
W	8,28	4,74	2,25

Samples after treatment in HNOS amples ready for ICP_OES analysis

Element calibration



lame:	Be	
Vavelength:	Be 234.861 nm	
ation Units:	ppm	
alibration:	31/10/2019 10:10:56	
t:	31/10/2019 10:10:56	
t:	Linear	
n:	1.0000	
:):	-8.167	
	50,610	C
ture):	0.0000	
ent):	1.000	
eslope	QC Normalize	
1.000	Slope factor:	1.000
0.0000	Offset:	0.0000





